



Quantum Resistance Metrology

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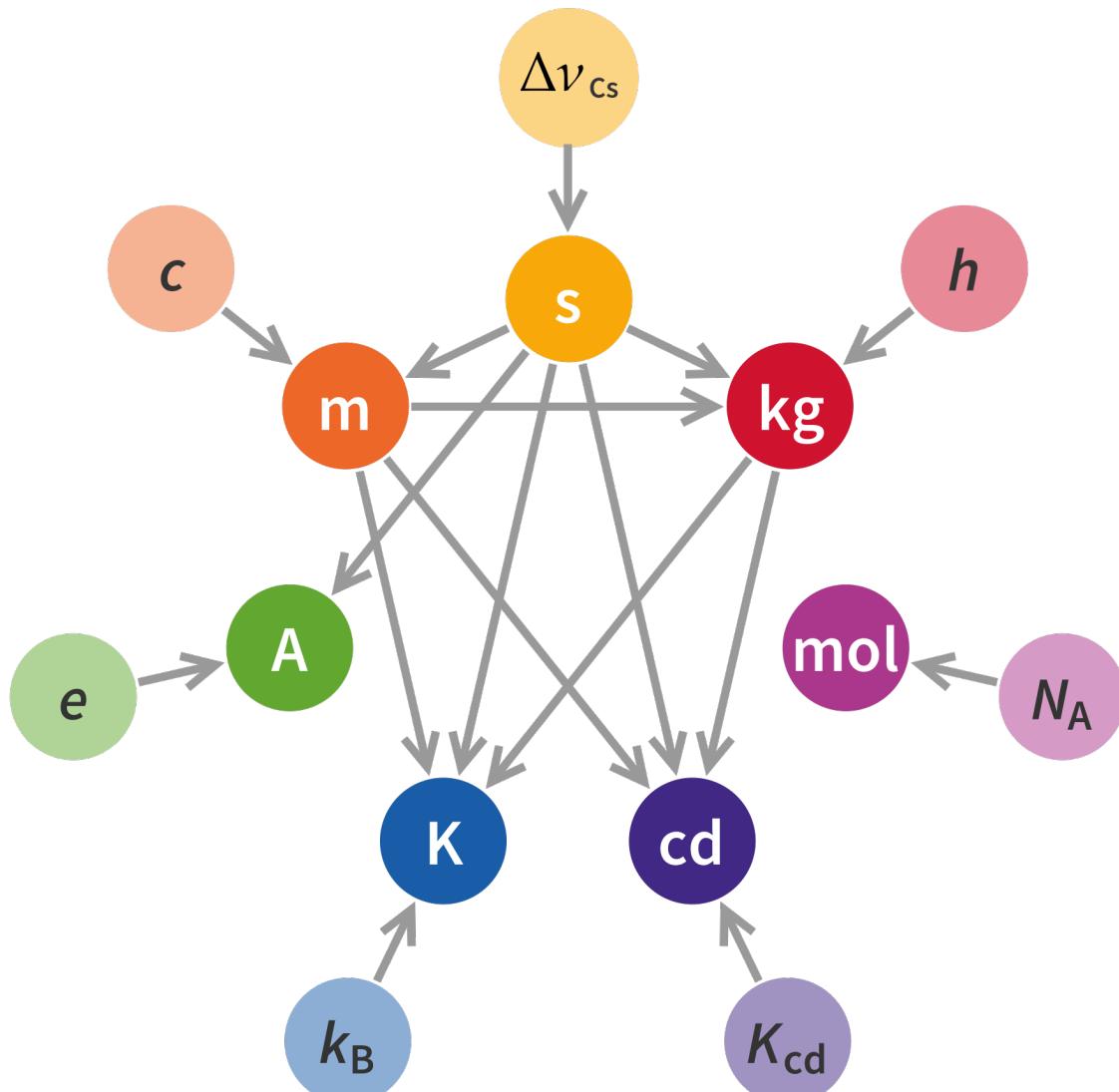


Redefinition of SI ADOPTED

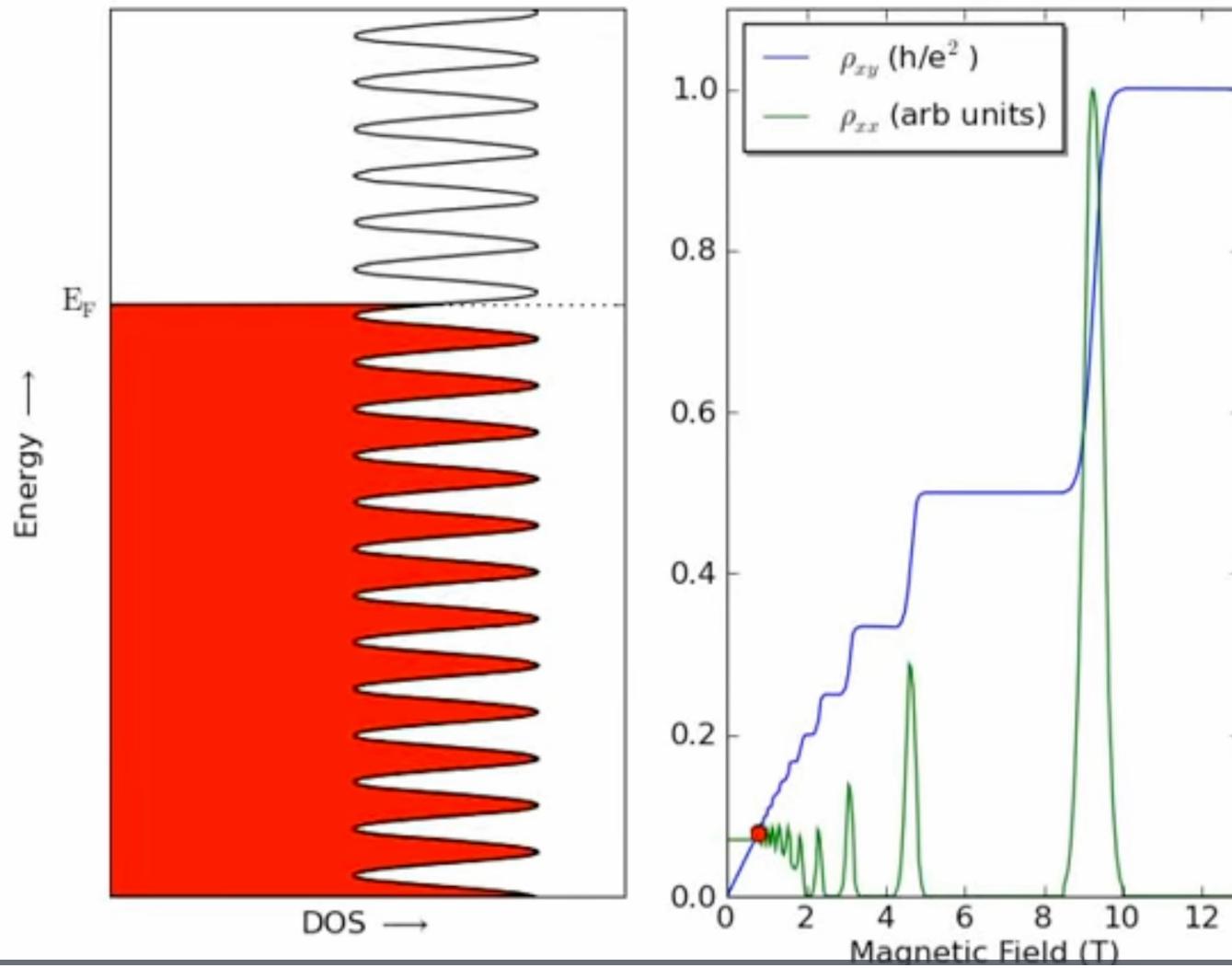
A vote happened on November 16, 2018, at Versailles, France.

The change went into effect on May 20, 2019.

Redefinition of SI in terms of true invariants of nature



Integer Quantum Hall Effect



01



Accuracy



$$\left(\frac{R_K}{2} - R_{xy} \right) / \left(\frac{R_K}{2} \right)$$

R_K is the von Klitzing constant (h/e^2)

02



Reproducibility



$$\frac{S}{\overline{R}_{xy}\sqrt{n}}$$

S is the standard deviation, n is the number of all data

03



Uncertainty

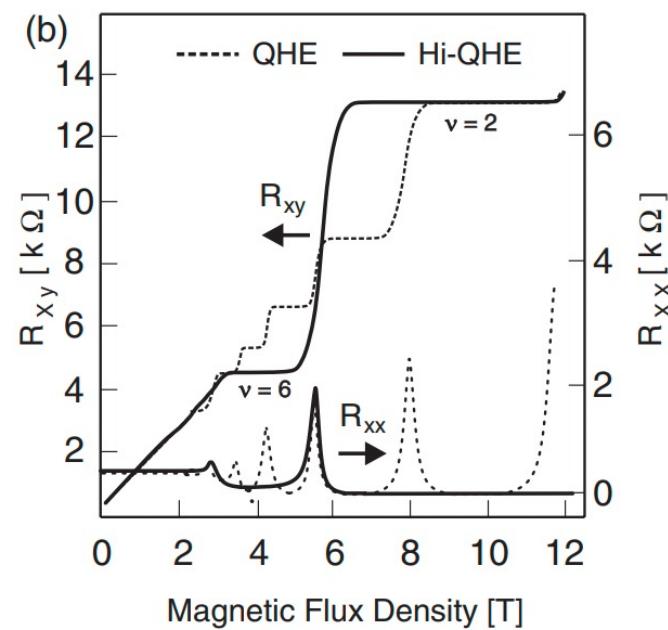
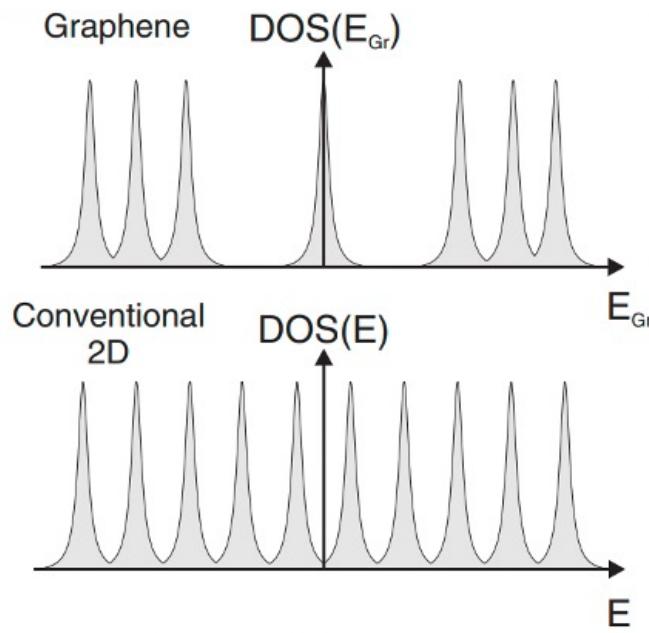


$$\frac{S}{\overline{R}_{xy}}$$

\overline{R}_{xy} is the average value of all the data measured

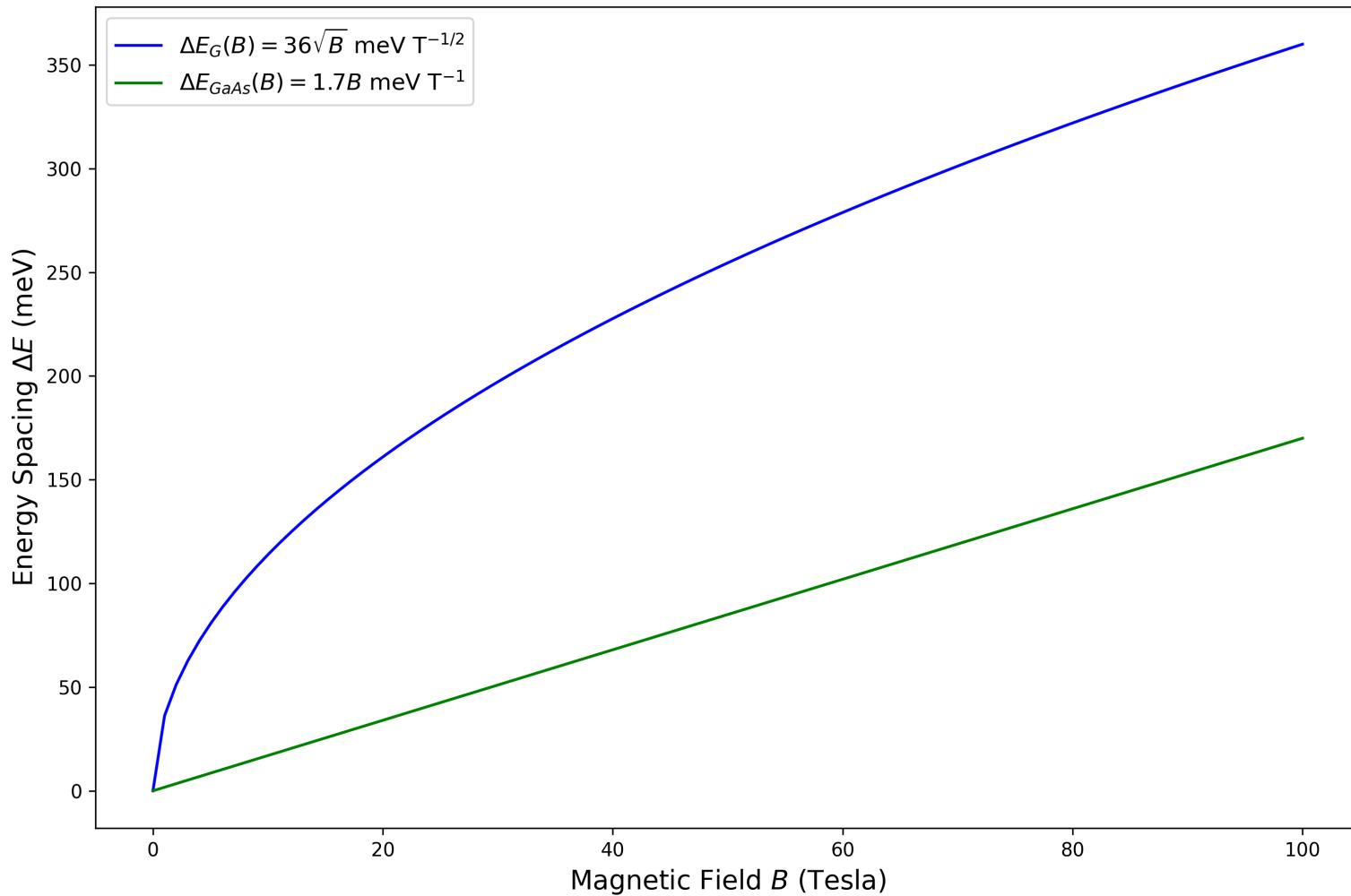
Unique Advantage of Graphene

Name	LL Spacing	Degeneracy	Unique N=0
Graphene	$\Delta E_{LL} \propto \sqrt{B}$	Spin and Valley	Half Electron Half Hole
GaAs	$\Delta E_{LL} \propto B$	Spin	None

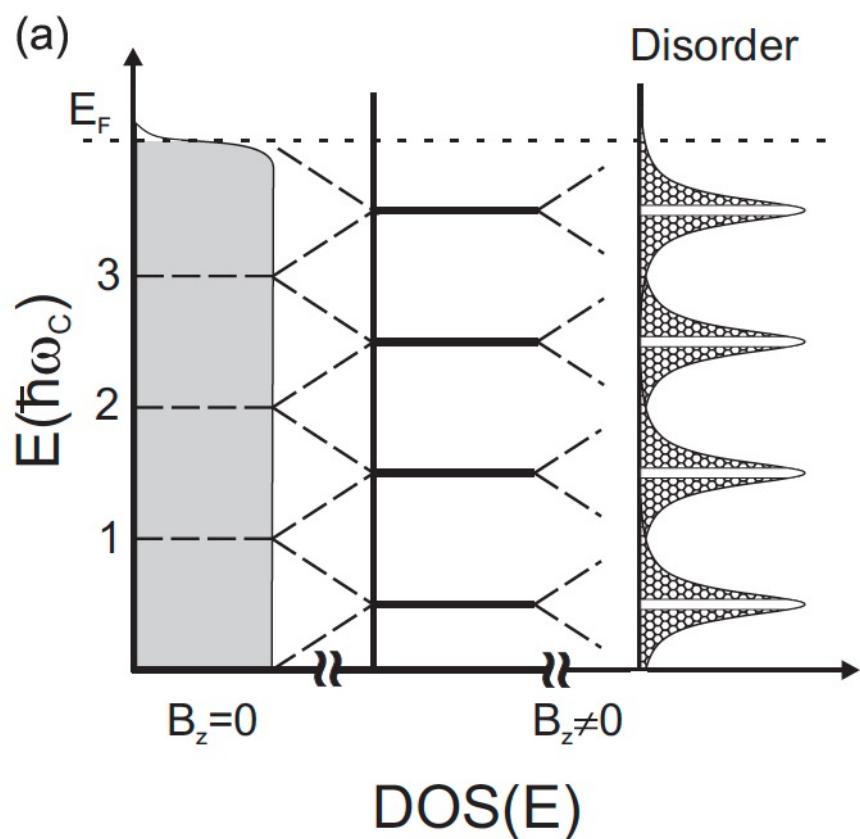


Breakdown field: $E_y = \sqrt{B\hbar\omega_c/e\tau_e}$ 13.6 times better Graphene vs GaAs

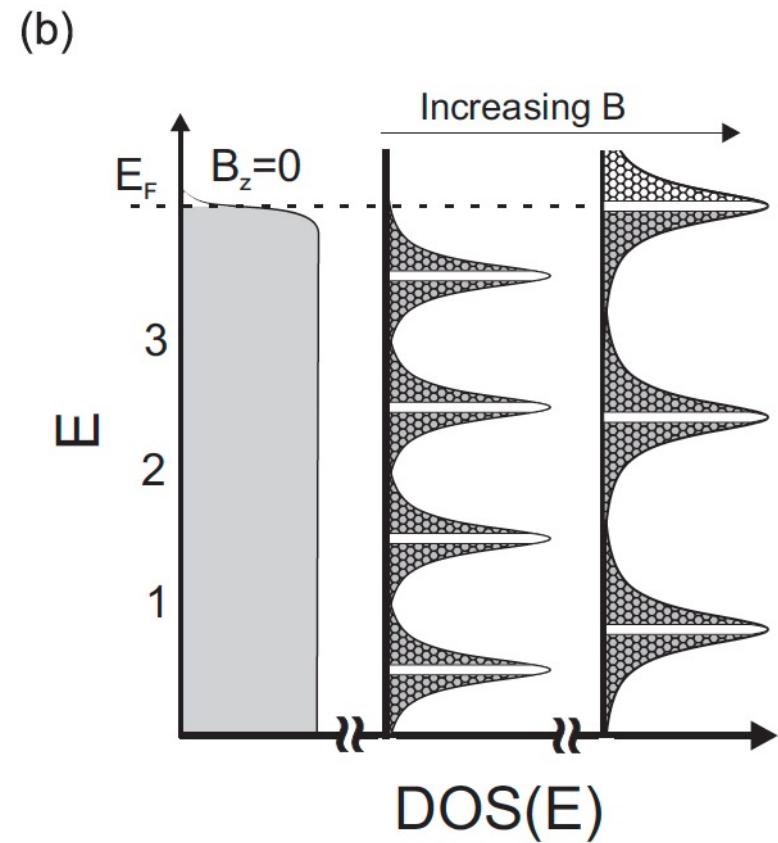
LL Spacing



Quantization of cyclotron motion leads to formation of LLs in the DOS

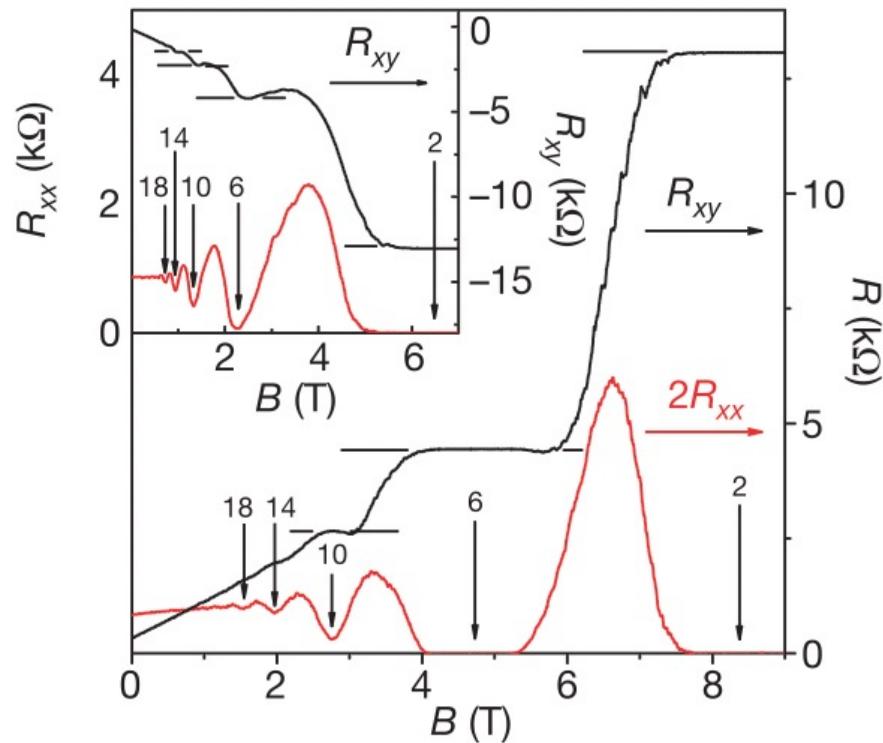
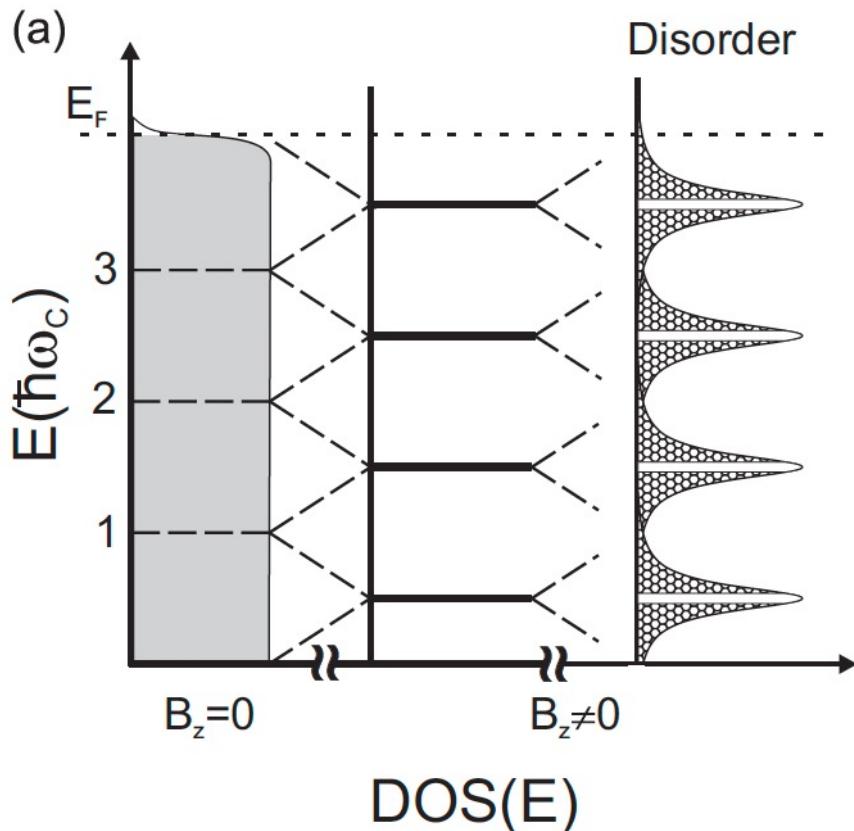


Varying E_F



Varying B

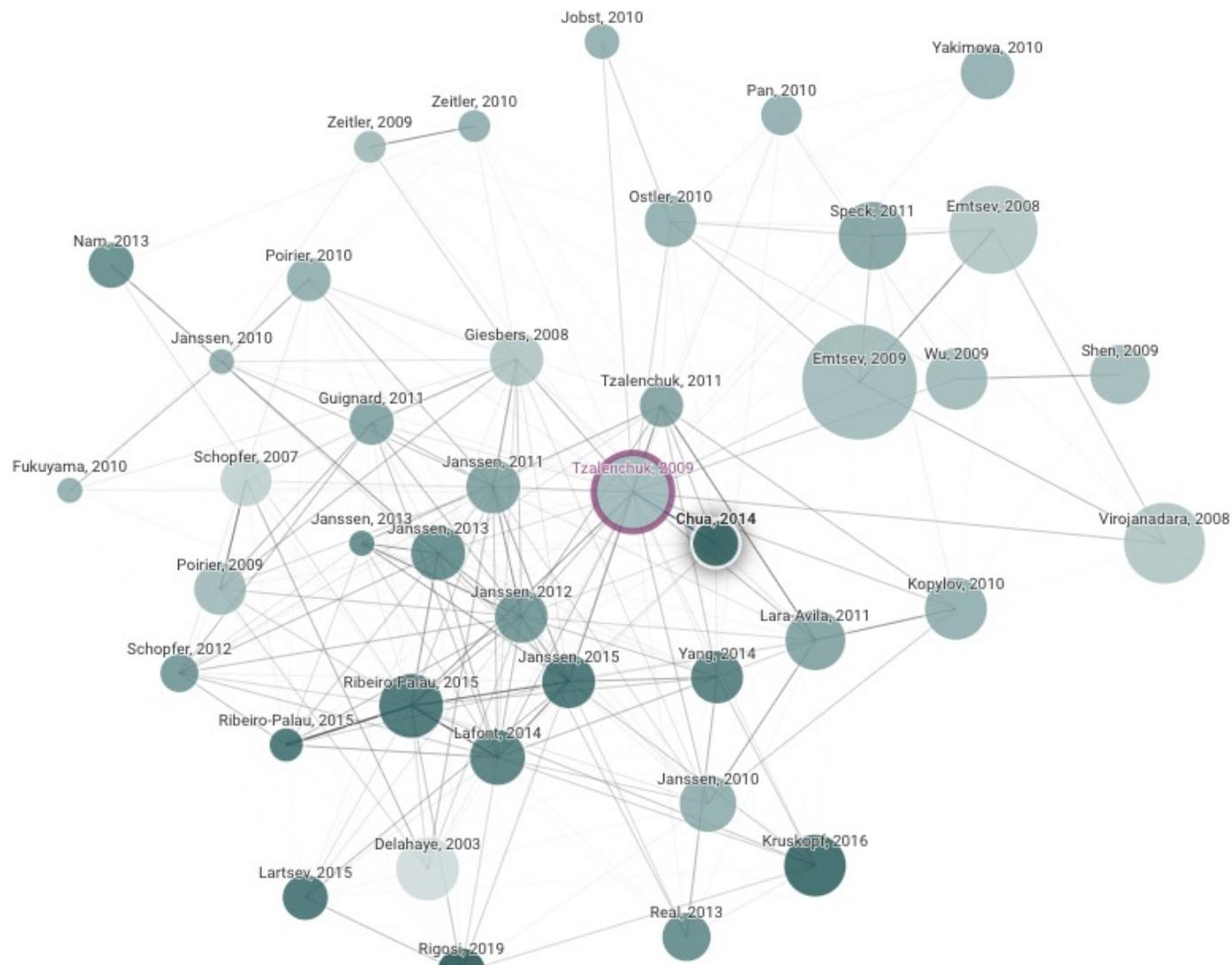
Mobility and Disorder

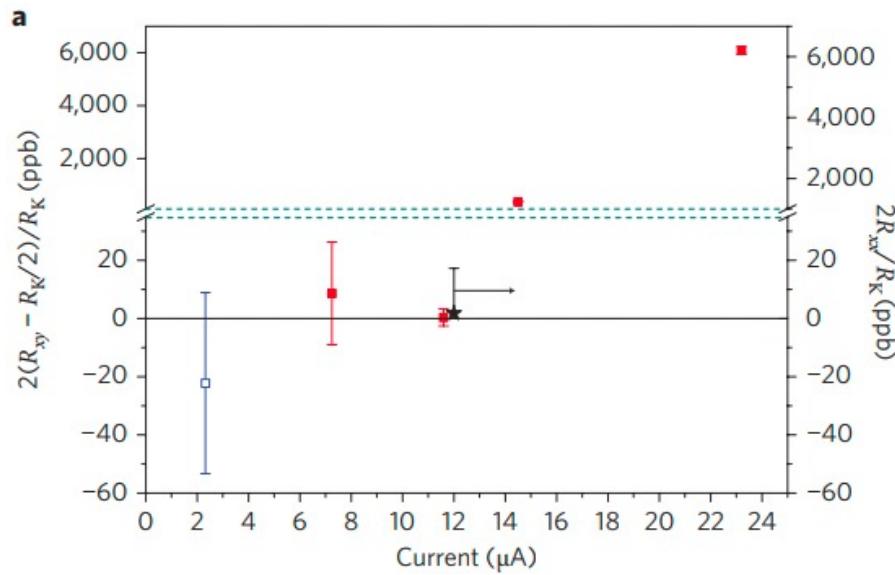
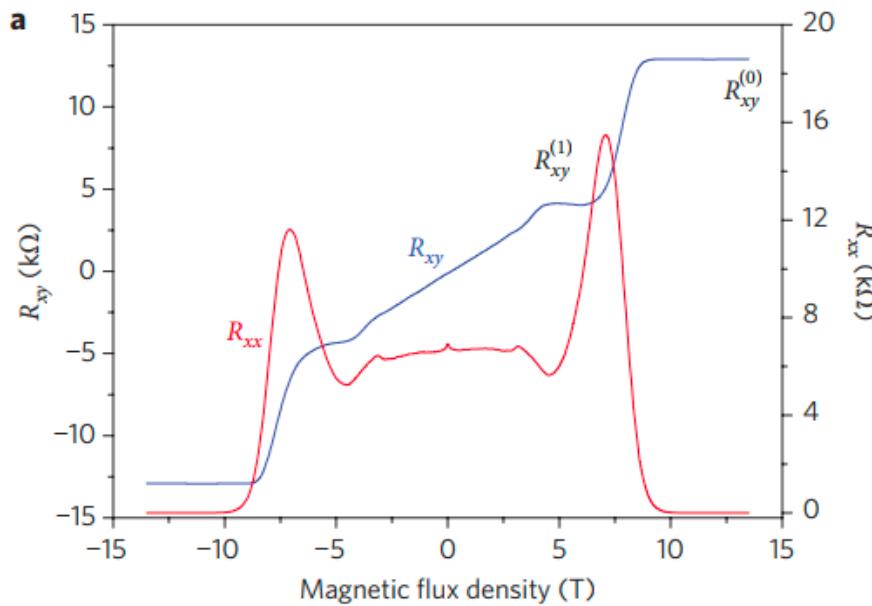


Nature 438.7065 (2005): 201-204

Disorder will broaden Landau levels (LL) and introduce scattering, which will reduce mobility!

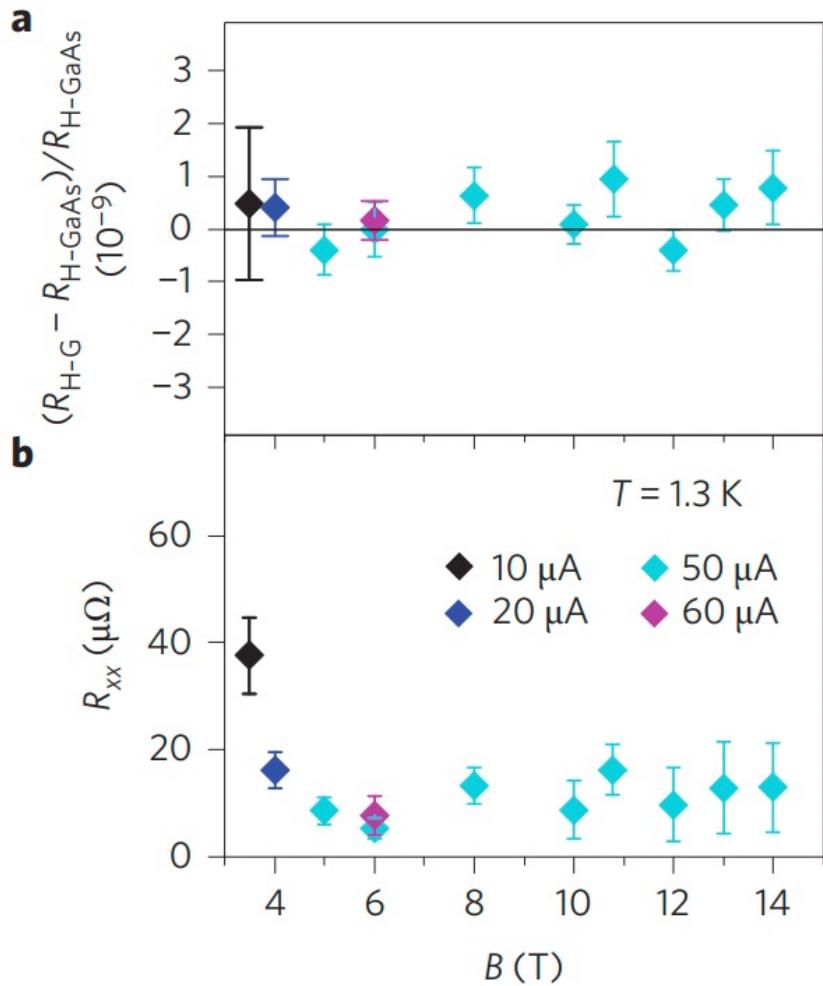
Citation Network



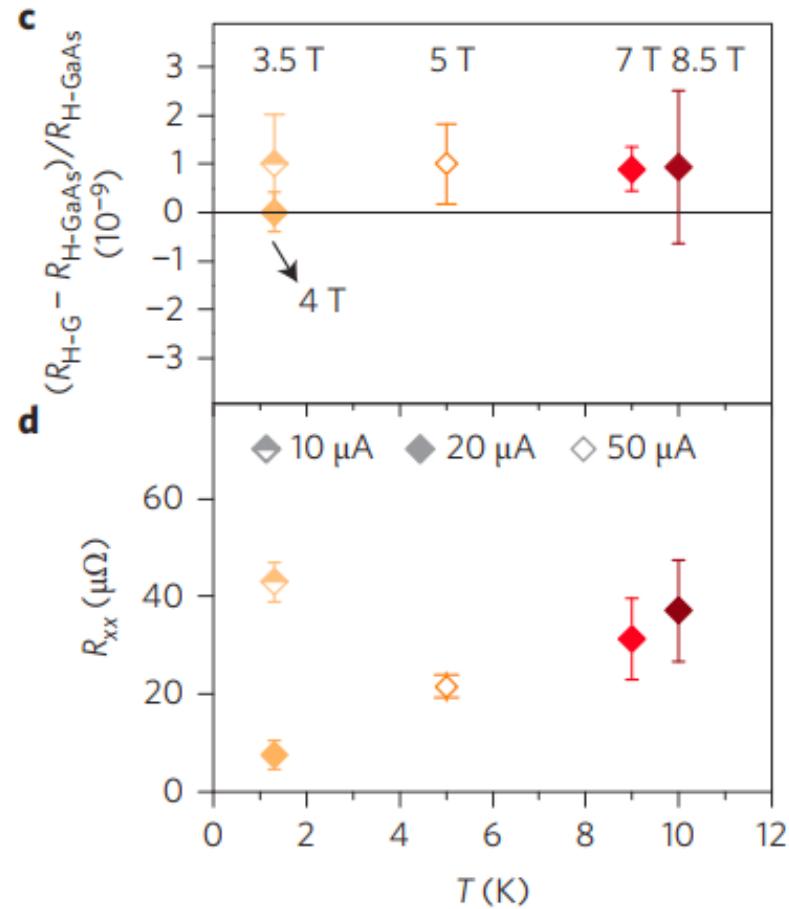


was achieved by Janssen and colleagues^{26–28}, who demonstrated excellent R_H accuracy to within 8.7×10^{-11} in epitaxial monolayer graphene grown by silicon sublimation from SiC by measurements mainly at $B = 14$ T and $T = 0.3$ K. However, these operational

MileStone 2

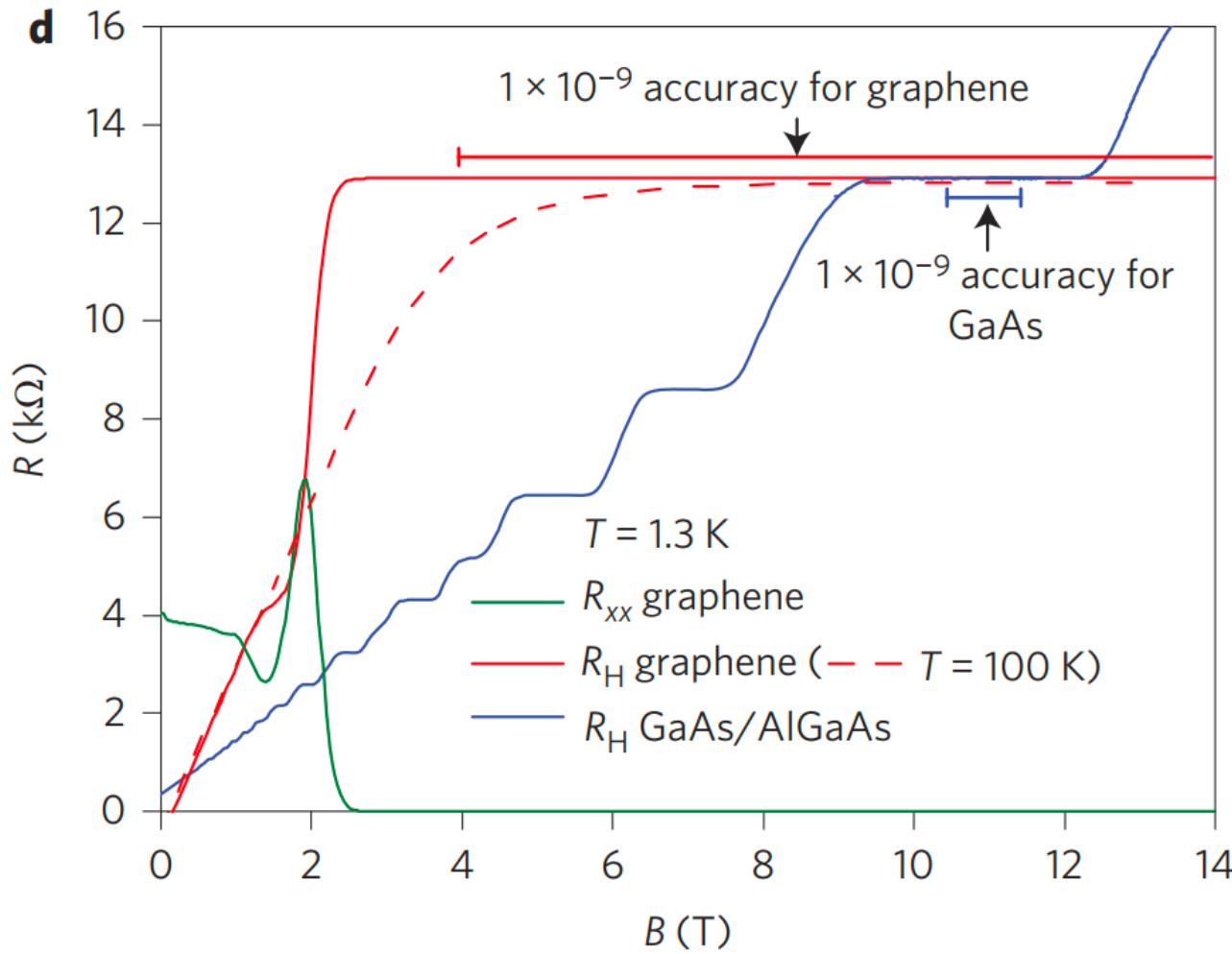


Accuracy: 10^{-9}

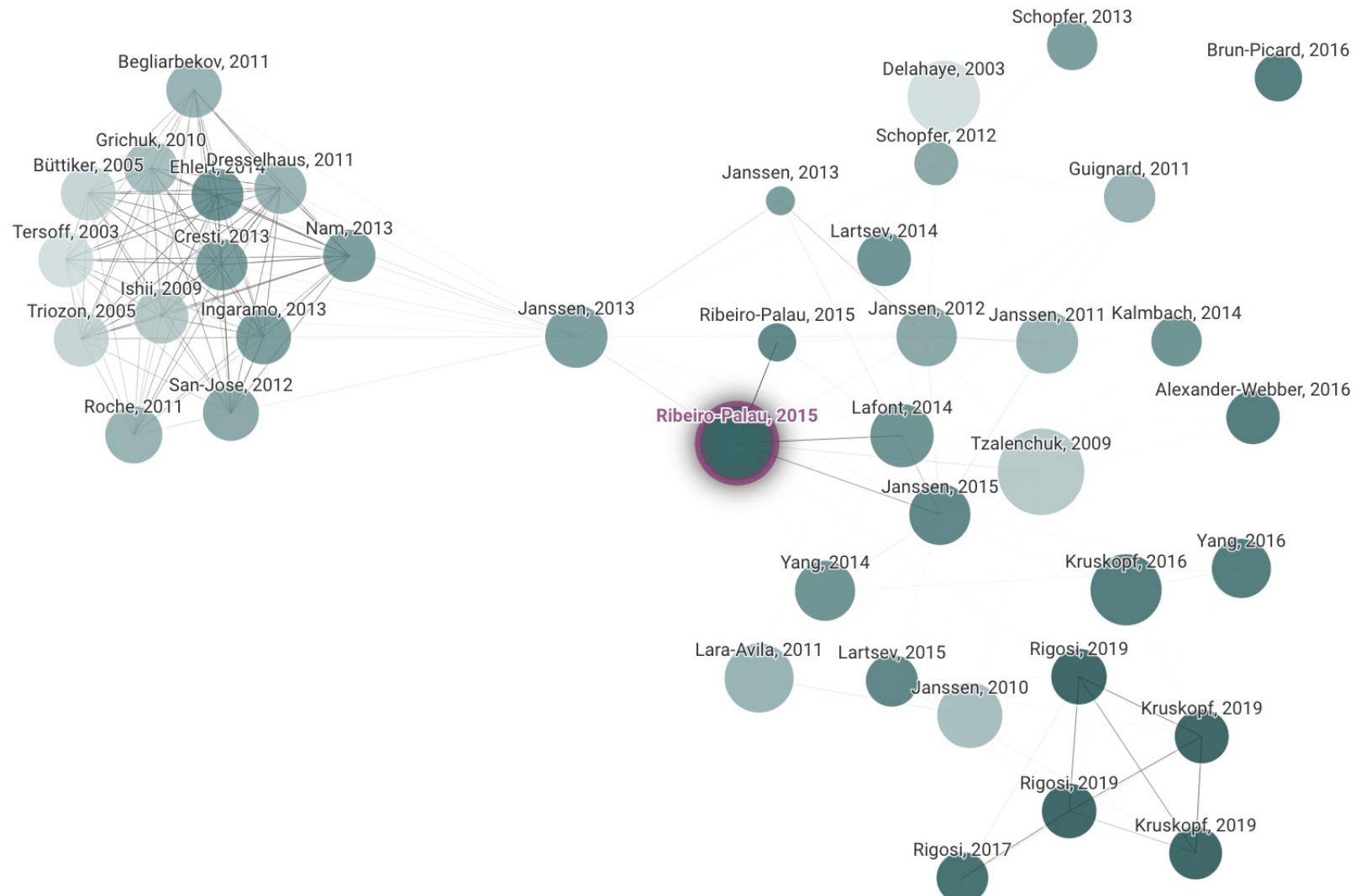


Uncertainty: 8.2×10^{-11}

State-of-the-art Graphene Resistance Metrology (GSM)



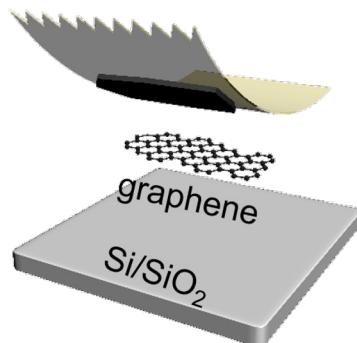
Citation Network



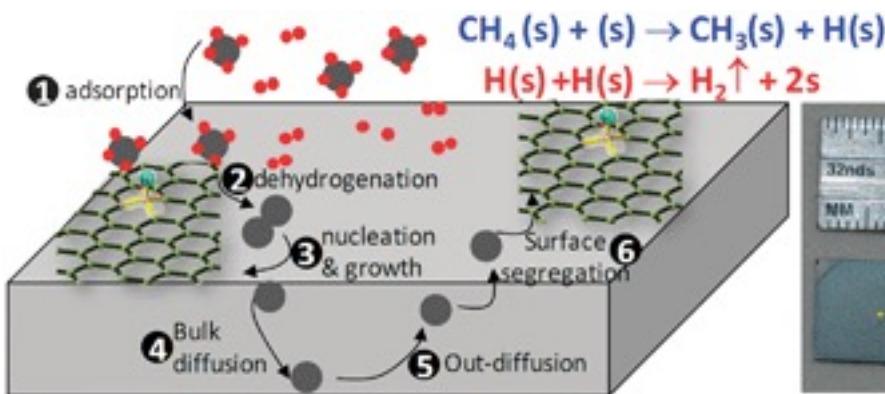
Graphene Fabrication Method

Exfoliation

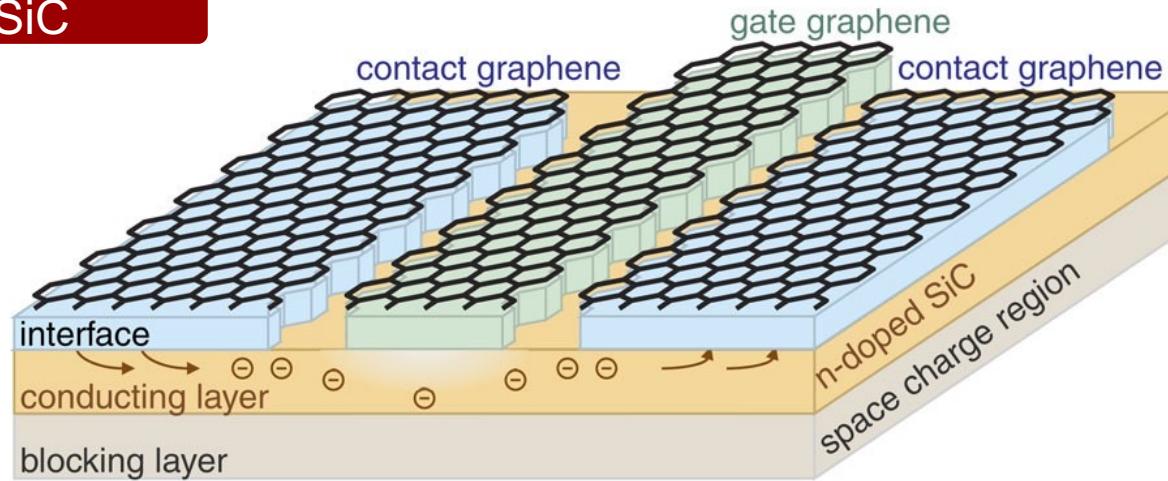
First Devices
Exfoliation to Si/SiO₂



CVD

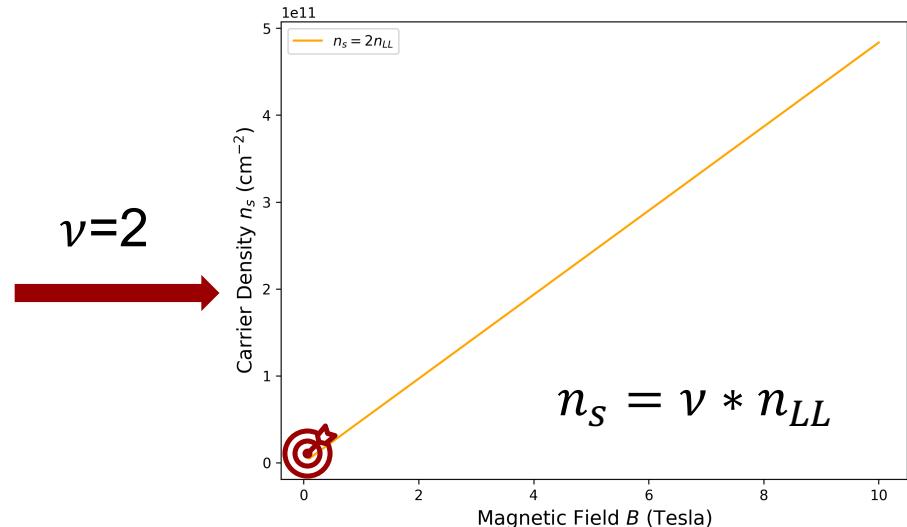
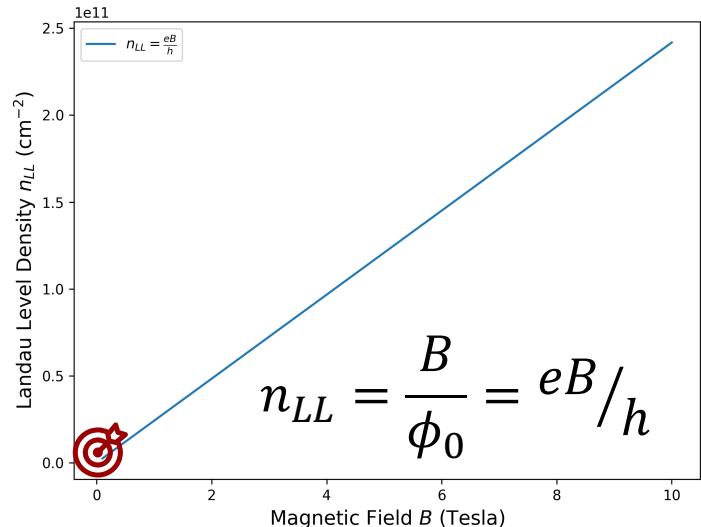


SiC



Challenges of Current Graphene Resistance Metrology

Name	Area	Doping (cm ⁻²)	Mobility (cm ² /Vs)
SiC Gr	Large	10 ¹² –10 ¹³	<10000
CVD Gr	Large	>10 ¹²	<10000
Exfo Gr	Small	~10 ⁹	>100000



$$\omega_c^{-1} \ll \tau \quad \longrightarrow \quad B \gg \mu^{-1}$$

Requirement of Graphene Resistance Metrology (GSM)

Target



A feasible magnetic field

A low carrier density



$\nu=2$ plateau E_F in-between
 $N=0$ and $N=1$ LL

FOM



High breakdown current

Small contact resistances



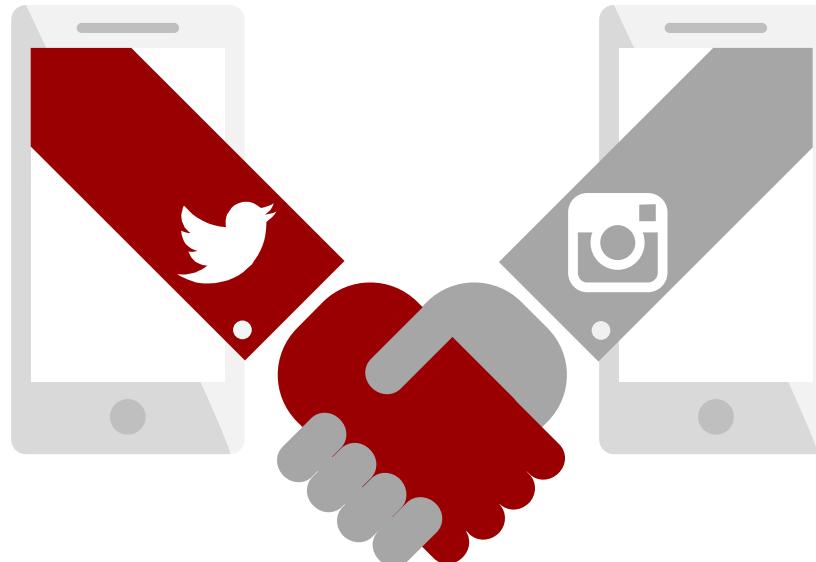
Large Area Graphene

High Doping

Maintain a high doping profile in the contact area while keeping a low-level doping inside the channel!

Disorder Reduction

Extrinsic Disorder inside:
Substrate
Buffer-layer
Interface



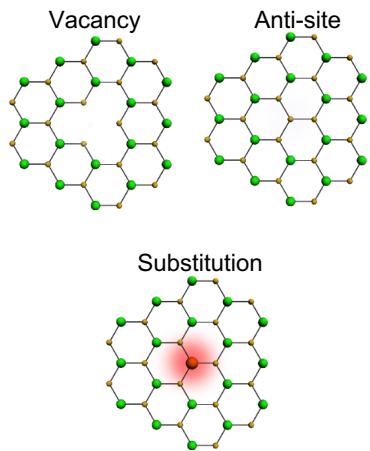
Doping Control

Doping control within:
Channel
Contacts
Transition region

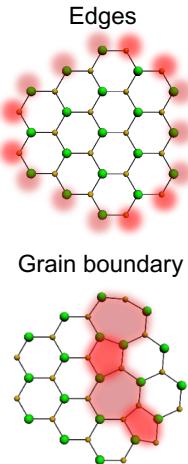
Interface control

Breakdown field: $E_y = \sqrt{B\hbar\omega_c/e\tau_e}$ 13.6 times better Graphene vs GaAs

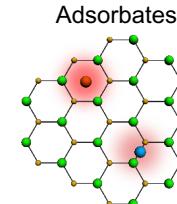
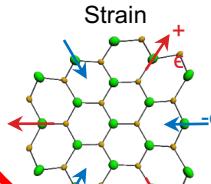
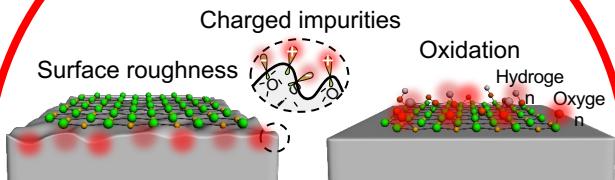
Point Defects



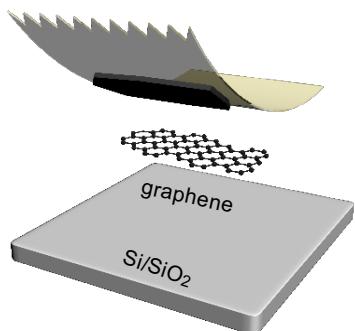
Termination



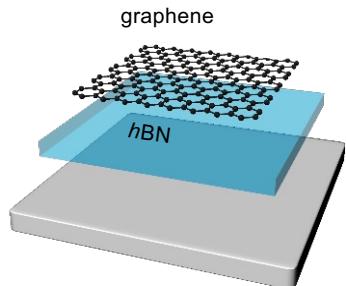
Extrinsic



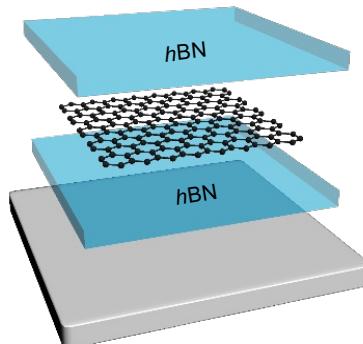
Gen 1
Exfoliation to Si/SiO₂



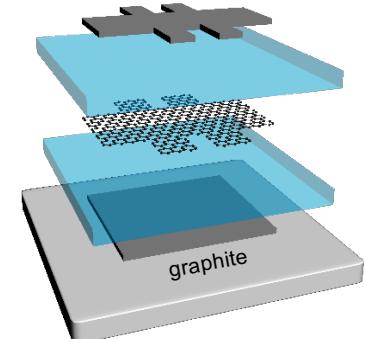
Gen 2
Polymer transfer to hBN



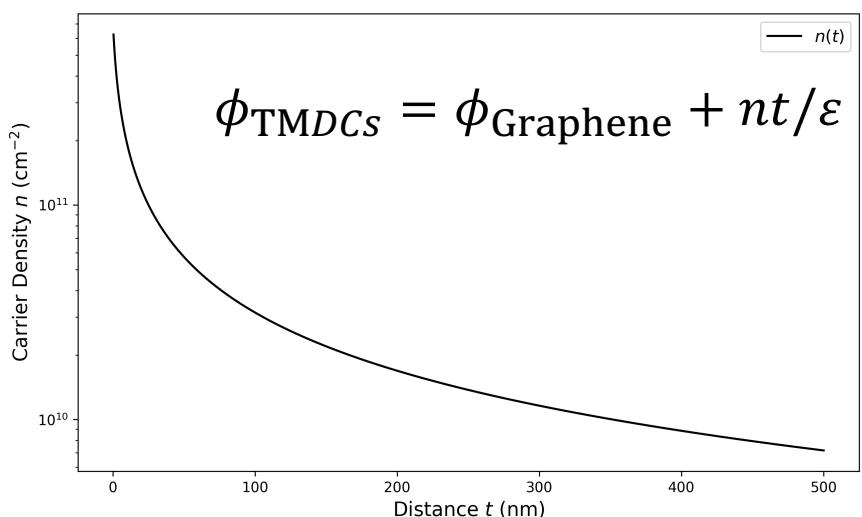
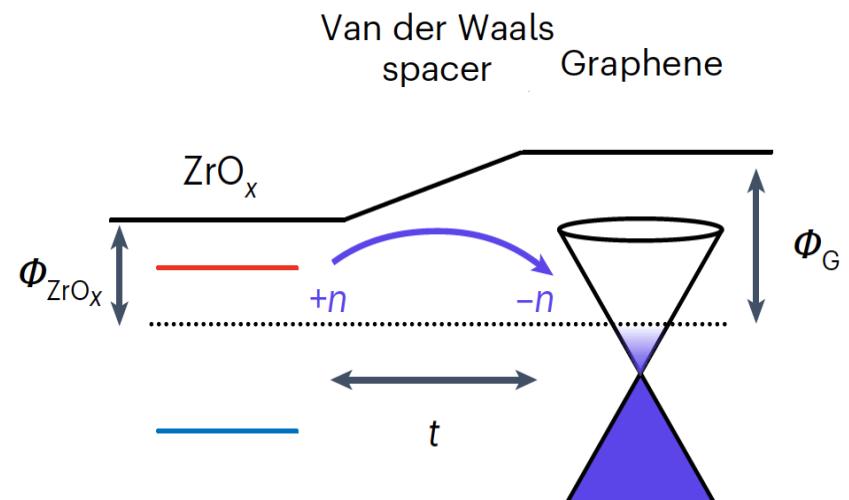
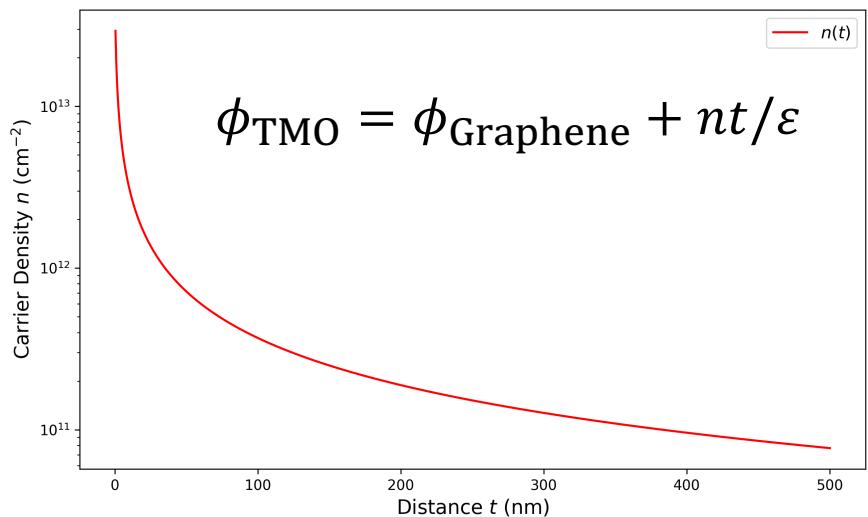
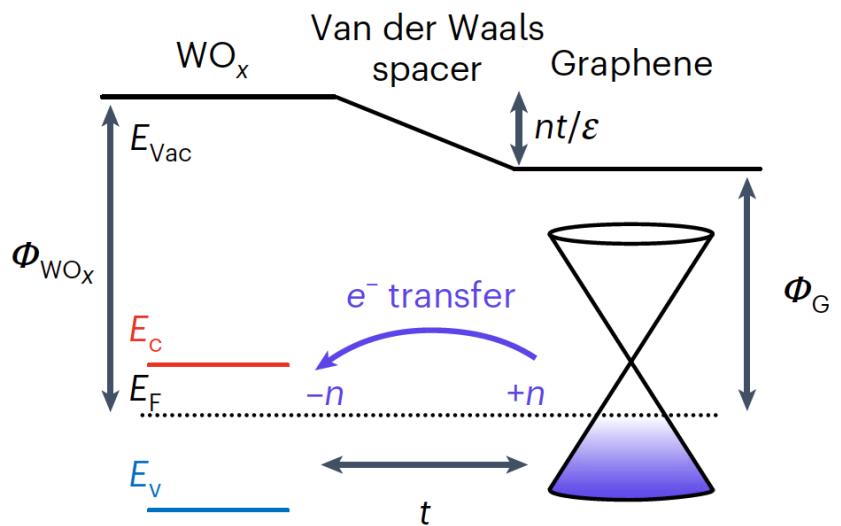
Gen 3
Dry encapsulation



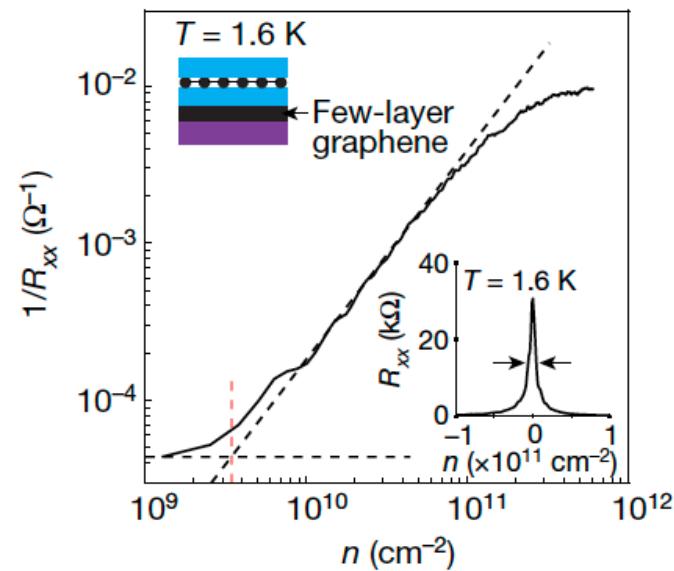
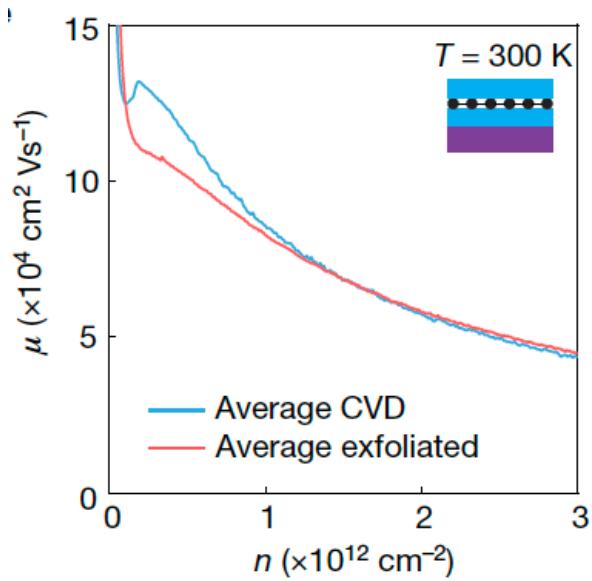
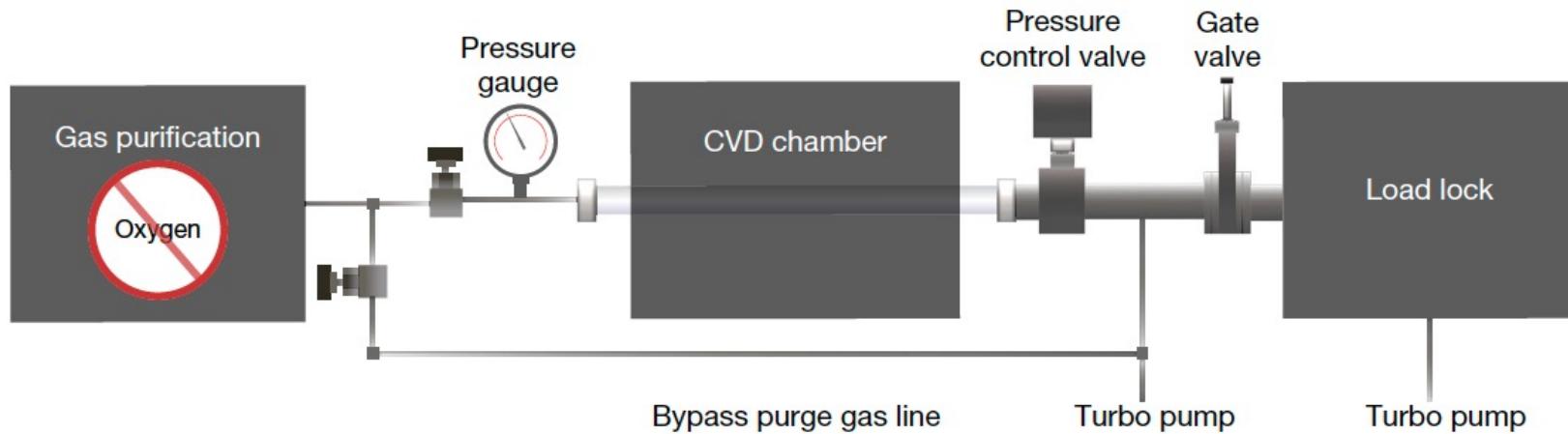
Gen 4
Graphite gating



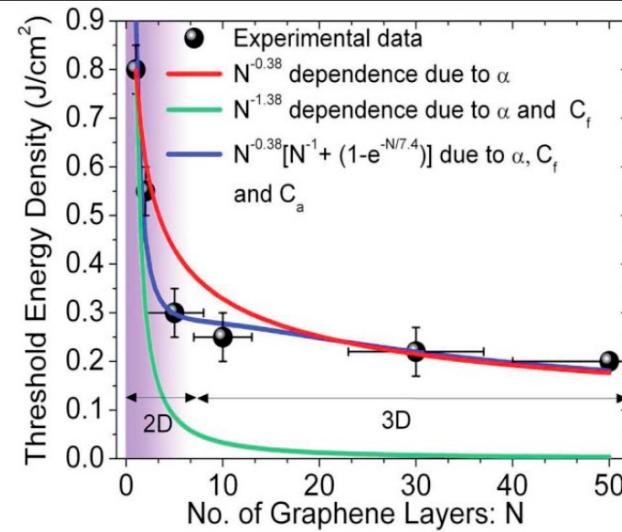
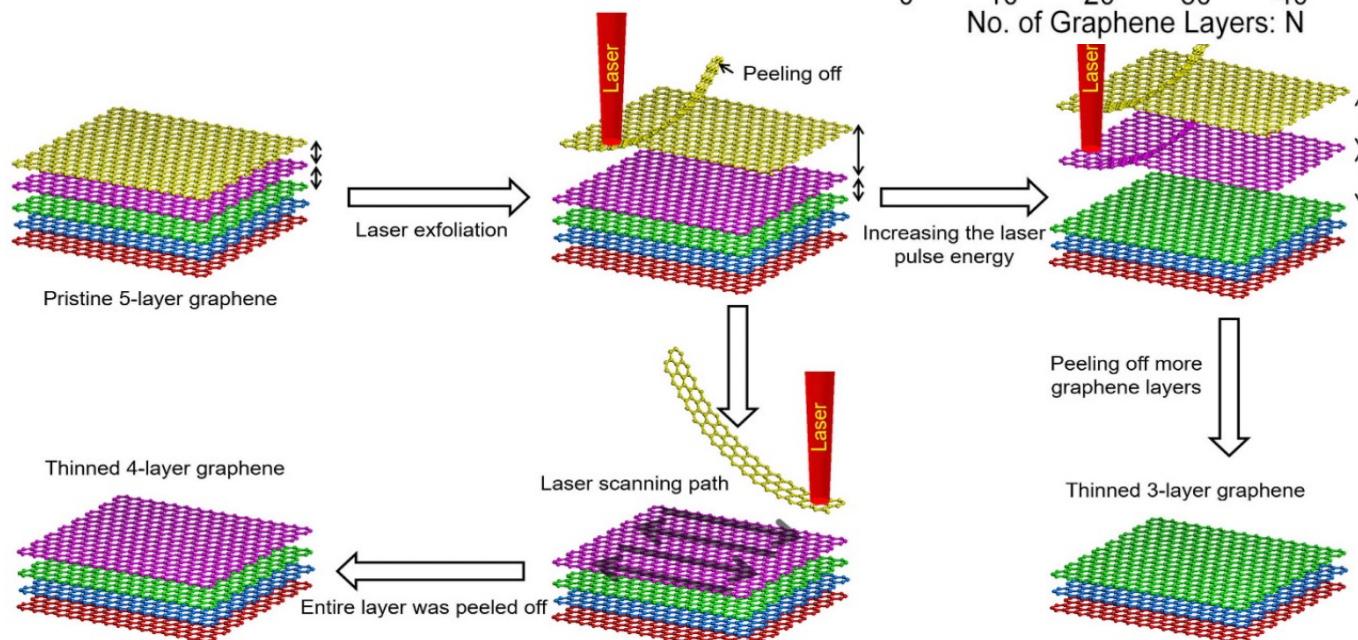
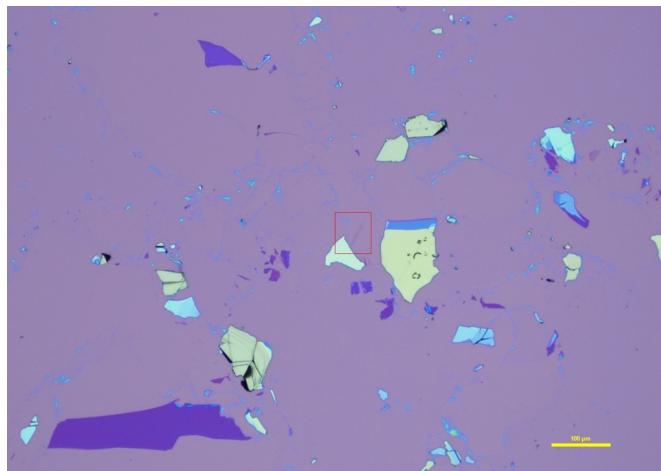
Doping Control – Research Basis



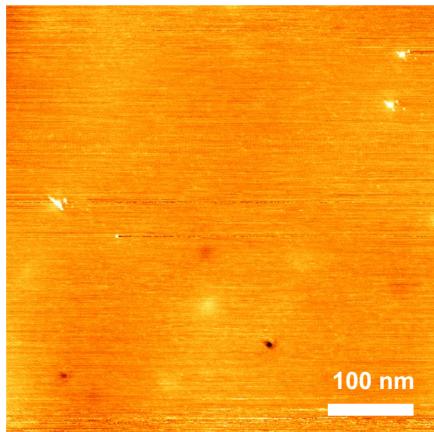
Interface Control – Research Basis of Raw Materials



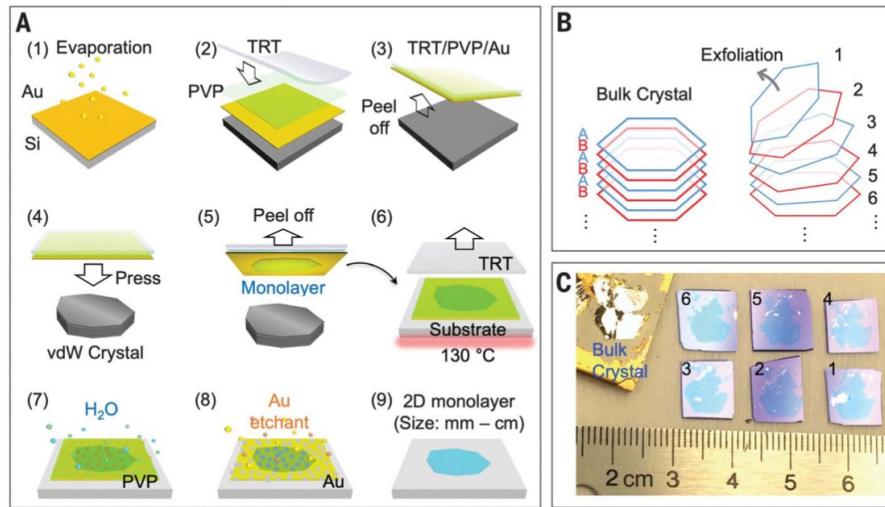
Interface Control – Research Basis of Raw Materials



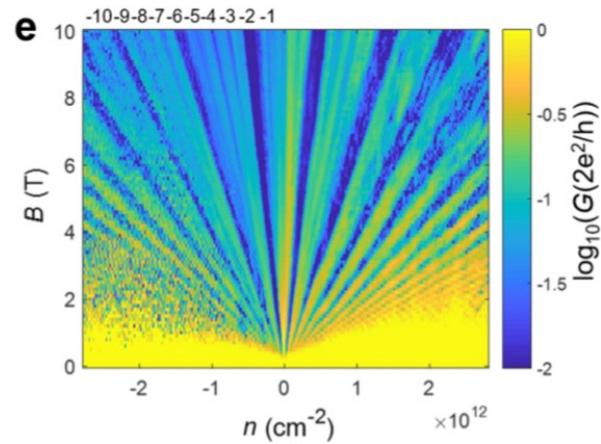
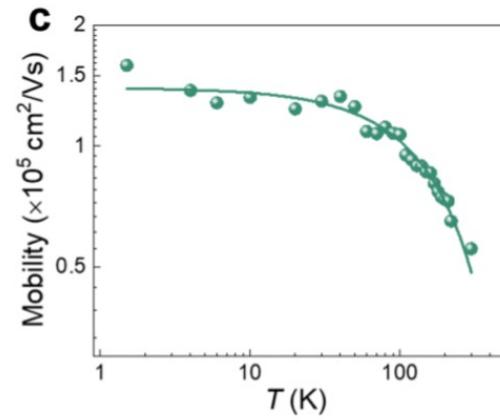
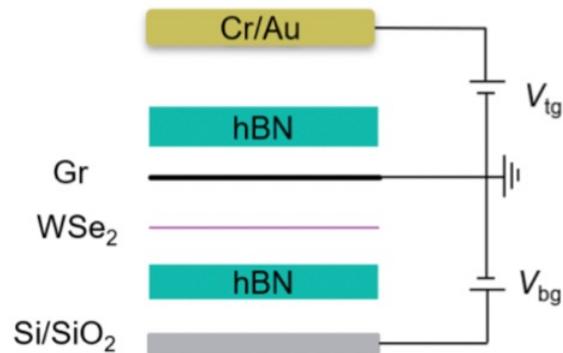
Interface Control – Research Basis of Raw Materials



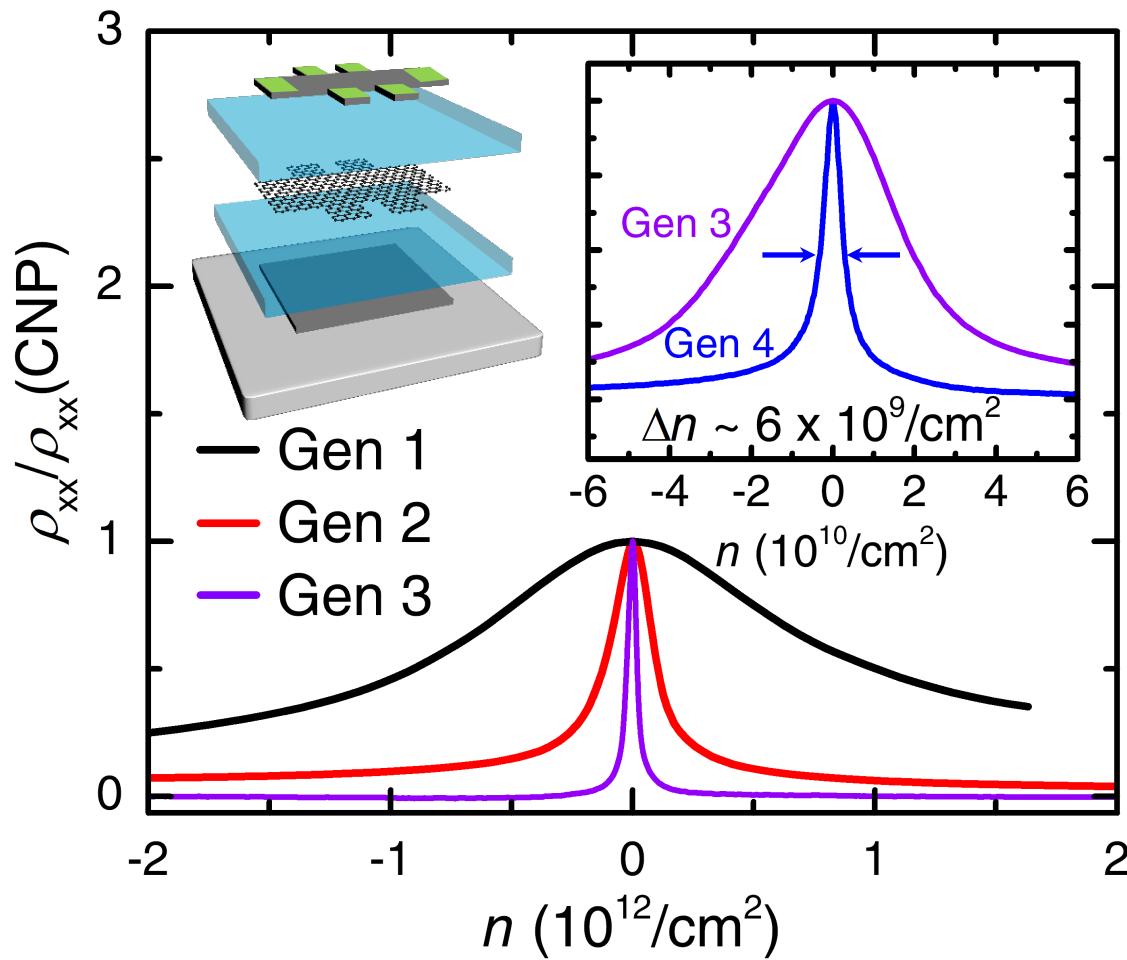
$\sim 3.8 \times 10^9 \text{ cm}^{-2}$



Science 367.6480 (2020): 903-906

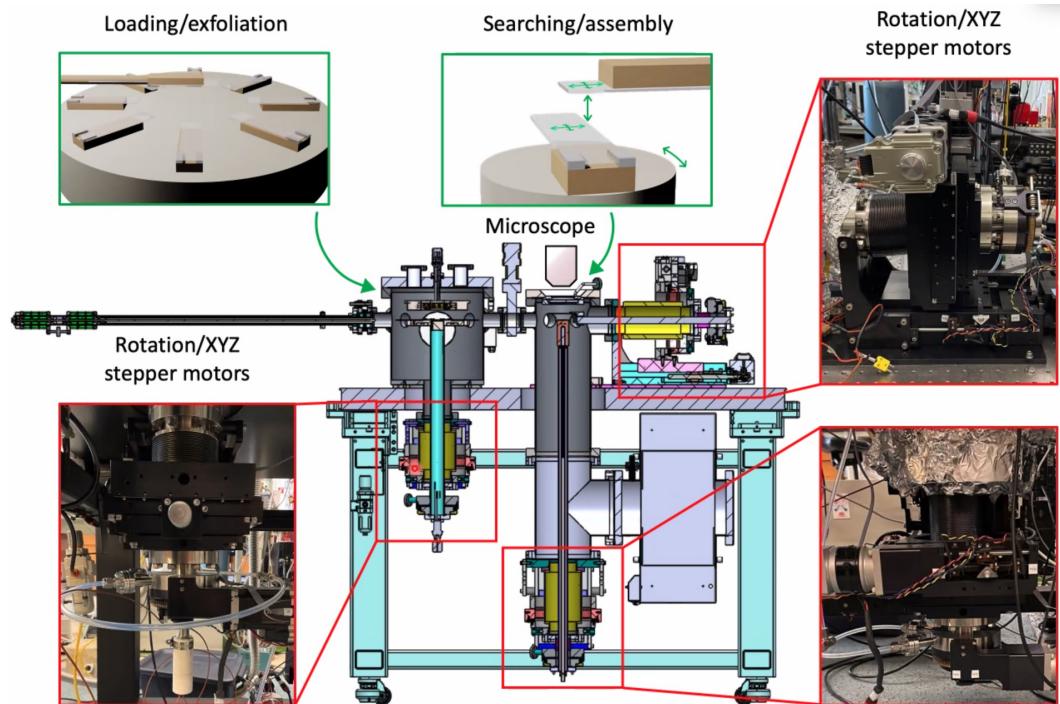
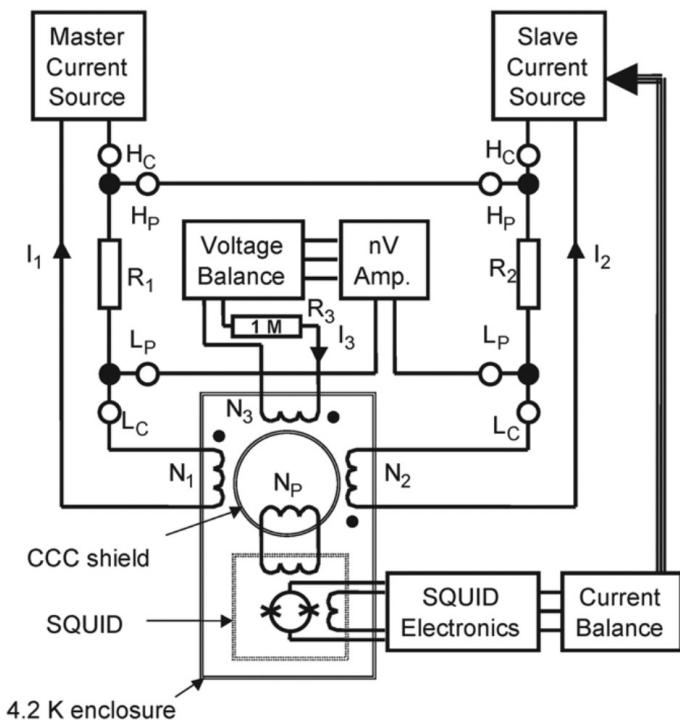


Spatially-Resolved Modulation doping



Spatially-Resolved Modulation Doping based on Ultraclean Quantum Materials!

Existing Obstacles & Solutions

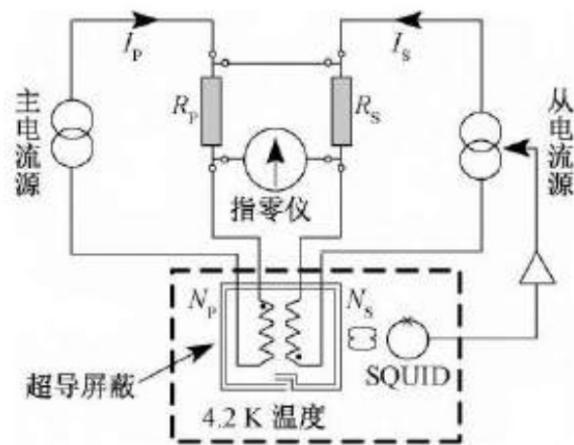


CCC Measurement Setup

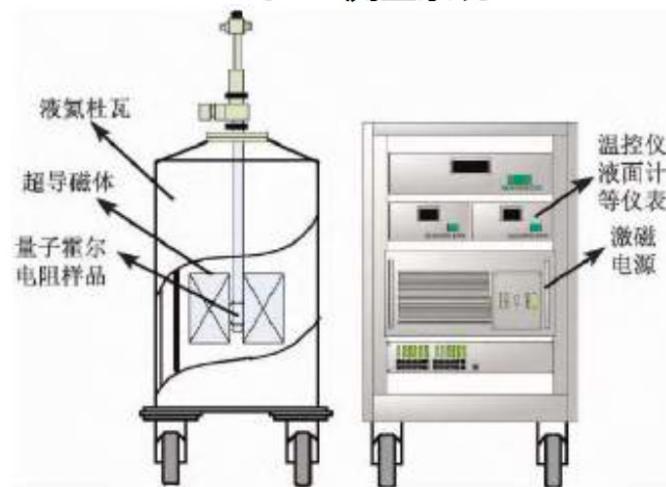
研究涉及的关键技术

关键技术问题3：量子电阻比对及测量不确定度抑制

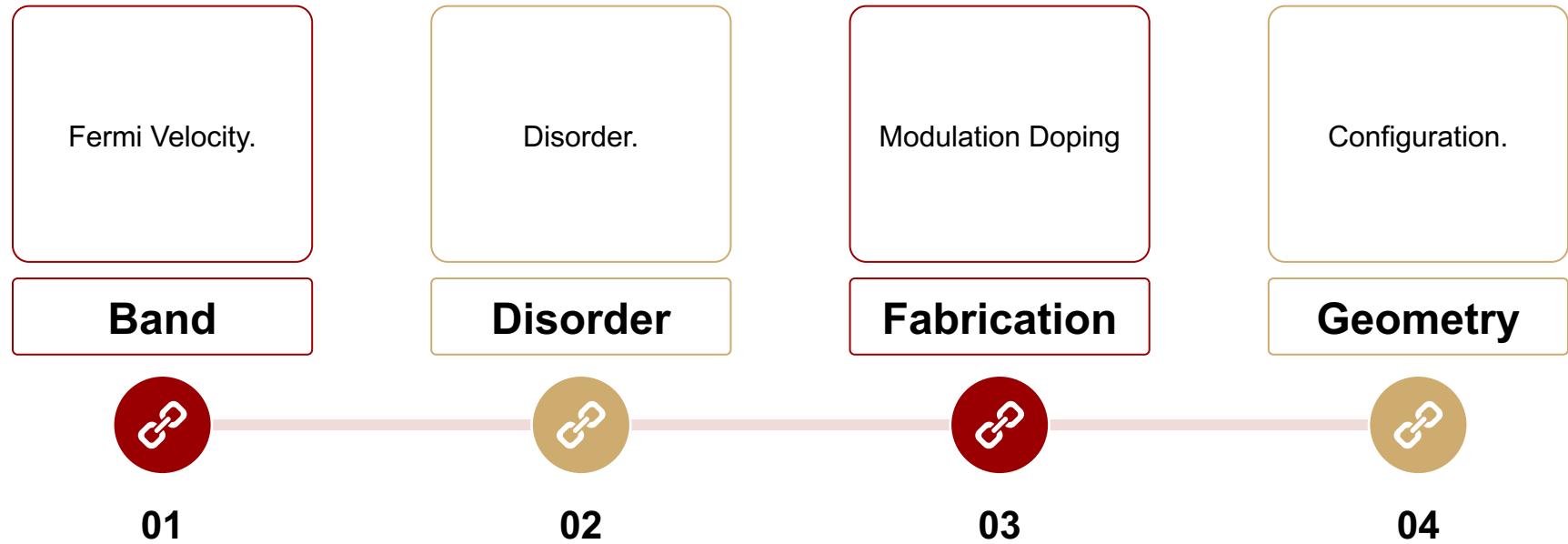
CCC电桥原理图



QHRS测量系统



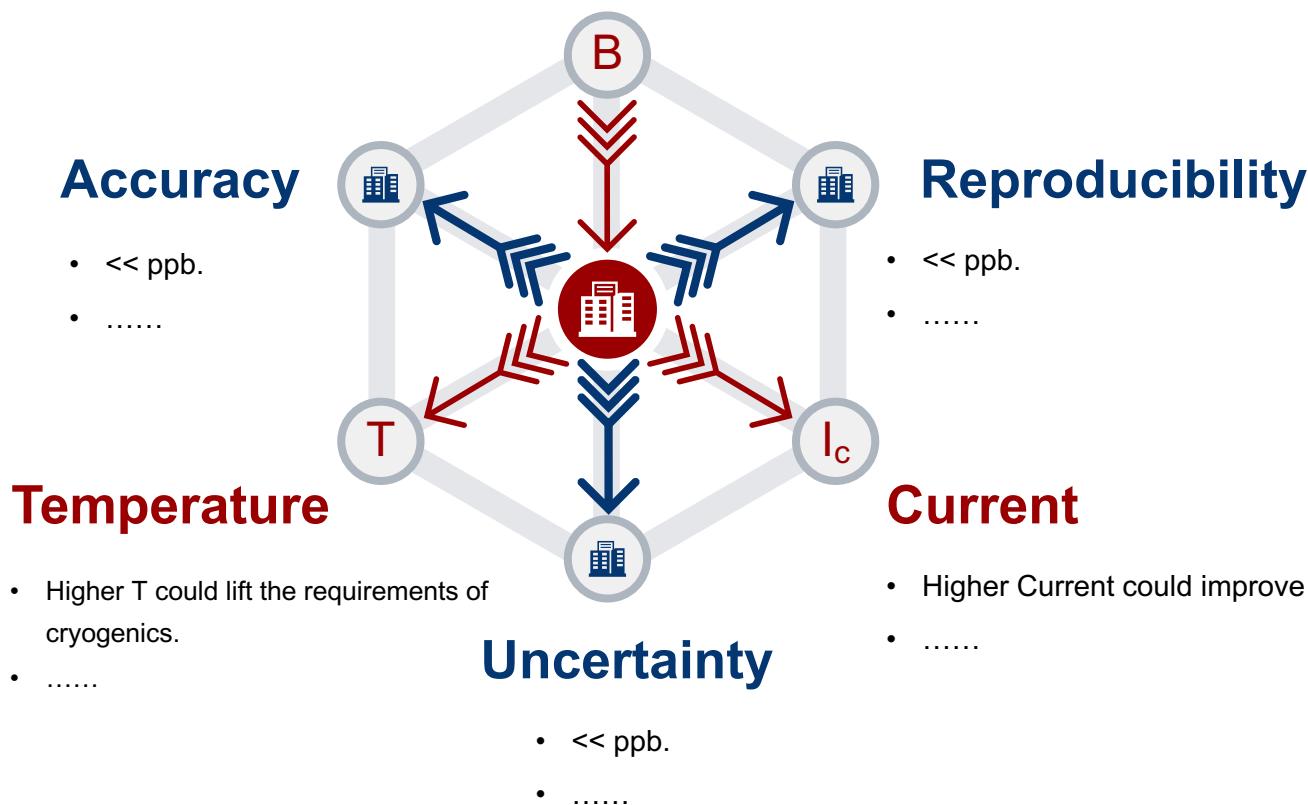
- CCC电桥易受外磁场干扰而失锁，要求低频磁屏蔽环境
- 比对电路易受制冷和磁场激励干扰，要求实现电磁屏蔽



Unified efforts are needed to drive it below the ppb level!

Magnetic Field

- The lower the better.
-





Thanks for your listening!